

JETLIGHT 50

Entry Level RTP System

Versatile, compact size and cost effective, software controlled bench-top type RTP tool, specifically designed to meet requirements of R&D laboratories and small-scale production units



POSSIBLE PROCESSES :

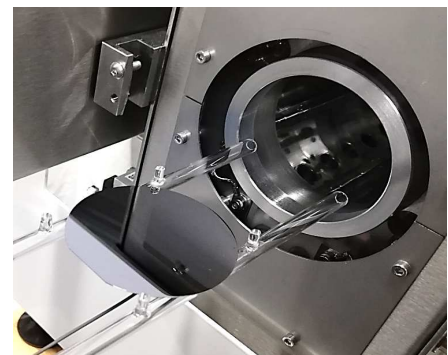
- _ Rapid thermal annealing (RTA), Oxidation (RTO)
- _ Nitridation (RTN), Diffusion (RTD)
- _ Implant monitoring
- _ Crystallization, Carbonization
- _ Contact alloying
- _ Stress relaxation

RTP MODULE CHARACTERISTICS :

- _ Quartz tube chamber
- _ 6 IR lamps heating system with tangential fan cooling
- _ Water-cooled reflector and flanges
- _ 16kW heating power and 3x400V+N+Gnd supply
- _ Temperature from Ambient to 1000°C
- _ Ramp rate from 1°C/sec to 50°C/sec
- _ Digital PID temperature control through TC K type
- _ Dimensions mm (LxWxH) : 600x685x535

KEY FEATURES :

- _ Software-controlled (PLC and PC)
- _ Hot-wall (quartz tube) chamber design
- _ 2 gas lines with manual ball flow meter control
- _ Substrate size up to 50mm diameter
- _ Quartz tubes substrate holder
- _ Atmospheric and vacuum process capabilities
- _ Microprocessor-based thyristor technology



MAIN STRENGTHS :

- _ Low cost versatile tool for a large range of applications, ideal for research labs
- _ Easy control of temperature profiles to adjust the process
- _ Quartz support for other sizes of substrate on request
- _ Process at atmospheric pressure or under vacuum
- _ Standard equipment allowing short delivery time